

1. Record Nr.	UNINA9910141275103321
Titolo	Advanced dielectric, piezoelectric and ferroelectric thin films [[electronic resource]] : proceedings of the 106th Annual Meeting of the American Ceramic Society, Indianapolis, Indiana, USA (2004) // editors, Bruce A. Tuttle ... [et al.]
Pubbl/distr/stampa	Westerville, Ohio, : American Ceramic Society, c2005
ISBN	1-280-67391-5 9786613650849 1-118-40720-2 1-118-40722-9
Descrizione fisica	1 online resource (98 p.)
Collana	Ceramic transactions ; ; v. 162
Altri autori (Persone)	TuttleBruce
Disciplina	621.3815/2 621.38152
Soggetti	Thin films - Materials Thin film devices Electronic books.
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	"... selected papers from the Advanced Dielectric, Piezoelectric and Ferroelectric Thin Films Symposium held at the American Ceramic Society's 106th Annual Meeting, April 18-21, 2004 in Indianapolis, Indiana."--p. vii.
Nota di bibliografia	Includes bibliographical references and indexes.
Nota di contenuto	Advanced Dielectric, Piezoelectric and Ferroelectric Thin Films; Contents; Preface; Chemical Solution Deposition of CaCu ₃ Ti ₄ O ₁₂ Thin Films; The Temporal Effects in DC-Biased PbNb(Zr,Sn,Ti)O ₃ ; High Energy Density PLZT Thin Film Capacitors; Reliability Studies on Sputter Deposited Barium Strontium Titanate Thin Film Capacitors; Raman Study of Effects of Excess Bi Content in Metalorganic Derived Bi ₄ Ti ₃ O ₁₂ Films; High Dielectric Tunability Ferroelectric (Pb,Sr)TiO ₃ Thin Films for Room Temperature Tunable Microwave Devices; Fabrication of Self-Assembled Nanostructures of Microwave Dielectrics Epitaxial Phase Selection in the Rare Earth Manganite SystemMulti-Ferroic BiFeO ₃ Films Prepared by Liquid Phase Epitaxy and Sol-Gel Methods; Effect of Argon Addition During ECR Mode Nucleation of

Sommario/riassunto

Advances in synthesis and characterization of dielectric, piezoelectric and ferroelectric thin films are included in this volume. Dielectric, piezoelectric and ferroelectric thin films have a tremendous impact on a variety of commercial and military systems including tunable microwave devices, memories, MEMS devices, actuators and sensors. Recent work on piezoelectric characterization, AFE to FE dielectric phase transformation dielectrics, solution and vapor deposited thin films, and materials integration are among the topics included. Novel approaches to nanostructuring, characterization of m